SHEET 1 OF 1

INFORMATION DISCLOSURE CITATION PTO-1449			(	Customer Number 26615		ATTORNEY'S DKT NO. H1491  APPLICANT(S) Bin Yu et al.  FILING DATE September 3, 2003		APPLICATION NO.  Hnassigned 19,653,234  GROUP  Unassigned 28/8		
U.S. PATENT DOCUMENTS										
EXAMINER'S INITIALS	PATENT NO.	DATE		NAME			CLASS	SUBCLASS	FILING DATE	
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dhn	Xuejue Huang et al.: "Sub-50 nm P-Channel Fin FET," IEEE Transactions on Electron Devices, Vol. 48, No. 5, May 2001, pages 880-886.									
olha	Yang-Kyu Choi et al.: "Nanoscale CMOS Spacer FinFET for the Terabit Era," IEEE Electron Device Letters, Vol. 23, No. 1, January 2002, pages 25-27.									
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).